

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10828437			
<b>Filing Date:</b>	21-Apr-2004			
<b>Title of Invention:</b>	Plasma processing apparatus, focus ring, and susceptor			
<b>First Named Inventor/Applicant Name:</b>	Shosuke Endoh			
<b>Filer:</b>	Marvin Jay Spivak/Emebet Girma			
<b>Attorney Docket Number:</b>	252112US2			
Filed as Large Entity				
<b>Utility under 35 USC 111(a) Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
Submission- Information Disclosure Stmt	1806	1	180	180
<b>Total in USD (\$)</b>				<b>180</b>